

Strain enhancement for a MoS₂-on-GaN photodetector with an Al₂O₃ stress liner grown by atomic layer deposition

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Strain regulation as an effective way to enhance the photoelectric properties of two-dimensional (2D) transition metal dichalcogenides has been widely employed to improve the performance of photovoltaic devices. In this work, tensile strain was introduced in multilayer MoS₂ grown on GaN by depositing 3 nm of Al₂O₃ on the surface. The temperature-dependent Raman spectrum shows that the thermal stability of MoS₂ is improved by Al₂O₃. Theoretical simulations confirmed the existence of tensile strain on MoS₂ covered with Al₂O₃, and the bandgap and electron effective mass of six layers of MoS₂ decreased due to tensile strain, which resulted in an increase of electron mobility. Due to the tensile strain effect, the photodetector with the Al₂O₃ stress liner achieved better performance under the illumination of 365 nm wavelength, including a higher responsivity of 24.6 A/W, photoconductive gain of 520, and external quantum efficiency of 8381%, which are more than twice the corresponding values of photodetectors without Al₂O₃. Our work provides an effective technical way for improving the performance of 2D material photodetectors. © 2020 Chinese Laser Press

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1. INTRODUCTION

Two-dimensional (2D) transition metal dichalcogenides (TMDs) have important research value in the fields of optoelectronic devices, energy storage, catalysis, etc., due to their special structure and excellent properties [1–7]. MoS₂, as a typical representative of TMDs, possesses a bandgap ranging from 1.80 eV (monolayer) to 1.20 eV (bulk), high mobility ($\sim 500 \text{ cm}^2 \cdot \text{V}^{-1} \cdot \text{s}^{-1}$), high light absorptivity, and thermal stability ($\sim 1100^\circ\text{C}$), which facilitate its applications in field effect transistors (FETs), photodetectors, and sensors [8–11]. Furthermore, its excellent mechanical property makes it useful in the application of related flexible and wearable devices. Although the carrier mobility for MoS₂ transistors is estimated to be $410 \text{ cm}^2 \cdot \text{V}^{-1} \cdot \text{s}^{-1}$ at room temperature by theoretical calculation [12], the experimental value is normally 1 or 2 orders lower, which significantly limits the performance of the transistors. Then many efforts, e.g., phase engineering [13], dielectric passivation [14], and boron nitride as back-gate dielectric [15], have been implemented to improve performance.

Current research indicates that the properties of 2D TMD materials, such as bandgap [16,17], effective carrier mass [18], conductivity [19], exciton–phonon coupling [20], and

spin-orbit coupling [21] can be changed by strain through changing the lattice structure (such as bond length, bond angle, and relative position of atoms) [22] and lattice symmetry [17]. Therefore, the strain regulation of 2D TMDs has aroused great interest from researchers. In the band structure of TMDs, the conduction band mainly comes from the contribution of the d_z^2 orbital of M , while the valence band mainly comes from the contribution of the d_{xy} , $d_{x^2-y^2}^{22}$ orbital of M and hybridization of P_x , P_y of X [23] [here, MX_2 represents TMDs, M is a transition metal element, and X is the VI main group element (S, Se, Te)]. When 2D TMDs have in-plane tensile strain, the band structure is changed, which in turn affects the properties of the material due to lattice being stretched, the distance between M and X being increased, the X – M – X bond angle being decreased, the relative position between the atoms being changed, and the state of the orbital overlap being changed. Li *et al.* calculated the relationship between the biaxial strain and the absorption spectrum with a strain range of 0%–9%, and found that the excitation energy decreased from 2.0 eV in the unstrained state to 1.1 eV under 9% biaxial strain [24]. It was found using density functional theory (DFT) that as the tensile strain on MoS₂ increases, the bandgap decreases,

the conduction band and valence band change due to changes in the lattice constant of the material, and the monolayer MoS₂ changes from a direct bandgap to an indirect bandgap, so strain affects the electron transition process in 2D TMDs [25]. Kis *et al.* reported that the piezoresistive gauge factor of monolayer MoS₂ is -148 ± 19 , indicating that the resistance decreases with increasing strain, which can induce the material to change from semiconducting to metallic [26]. Bending, stretching, compressing flexible substrates [18], diamond anvil cell (DAC) [27], and utilizing differences in thermal expansion coefficients of a substrate [28] can be used as ways to induce strain. MoS₂, which is directly grown on a patterned sapphire substrate (PSS) by chemical vapor deposition (CVD), is subject to compressive strain after rapid temperature drop due to the difference in the thermal expansion coefficient [29]. Strain from mechanical external forces is unstable and uncontrollable and may even damage the integrity of the film. Differences in the lattice constants or thermal expansion coefficients between the substrate and 2D TMDs degrade the quality of grown film. Kufer and Konstantatos reported highly stable and high-performance monolayer and bilayer MoS₂ photodetectors encapsulated by atomic layer-deposited HfO₂ with vanishing hysteresis and reduced device resistance [30]. Even when using scandium contacts on 10-nm thick exfoliated MoS₂ flakes that are covered by a 15 nm Al₂O₃ film, high effective mobility of $700 \text{ cm}^2 \cdot \text{V}^{-1} \cdot \text{s}^{-1}$ is achieved at room temperature [31]. The improvement of the material and device performance induced by the high-*k* dielectric has been primarily attributed to the screening effect on the charged impurity scattering. As a result of first-principles calculation, about 0.41% tensile strain on monolayer MoS₂ can be introduced by 3 nm Al₂O₃ covering the surface [32]. This implies that high-*k* oxide deposition on 2D TMDs can also introduce strain due to differences in their thermal expansion coefficients. Nevertheless, systematic and insightful studies about the effects of oxide strain layer on 2D TMDs are still essential and important to guide the development of strained TMD devices. It has been reported that the MoS₂ grown on GaN has a shorter effective exciton lifetime, which promotes fast photogenerated electron-hole separation and enables high responsivity and fast response of photodetectors [33–36].

Herein, high quality, large area, and continuous multilayer MoS₂ was successfully grown on a freestanding (FS) GaN substrate (350 μm thick) with (0001) orientation using the CVD method, and a 3 nm thick Al₂O₃ overlayer was deposited on it by atomic layer deposition (ALD), forming the heterostructure of Al₂O₃/MoS₂/GaN. Raman spectroscopy, X-ray photoelectron spectroscopy (XPS), and transmission electron microscopy (TEM) characterizations have been carried out to investigate the material. Then MoS₂-on-GaN photodetectors with and without the Al₂O₃ stress liner have been fabricated in typical semiconductor fabrication process and fully characterized. After the tensile strain is introduced by the Al₂O₃ stress liner, the performance of the photodetector, including photocurrent, responsivity, gain, and external quantum efficiency, is significantly improved.

2. METHOD

A. Preparation of the MoS₂ on GaN, Al₂O₃ and Photodetectors

High-quality multilayer MoS₂ is grown by CVD method on a transparent nondoped free-supporting GaN substrate with a size of 1 cm by 1 cm. Before growth, FS GaN substrate (350 μm thick) with (0001) orientation was cleaned with acetone (CH₃COCH₃, 99.5%), isopropanol (C₃H₈O, 99.5%), and deionized water in an ultrasonic instrument successively for 10 min, and then dried with high-purity N₂. During the growth process, the S molybdenum trioxide powder (MoO₃, 99.95%) and sulphur powder as precursors were heated to 250°C and 750°C, respectively, and kept at the temperature for 20 min. Finally, the temperature was naturally decreased to room temperature, and the entire process was continuously passed through Ar with the atmospheric pressure. Al₂O₃ was deposited on the surfaces of MoS₂/GaN and MoS₂ photodetectors by the ALD method at 250°C, in which precursors are H₂O and trimethyl aluminum (TMAI, 99.9999%). The photodetectors were fabricated through a standard photolithography (Suss MA6)-thermal evaporation (ASB-EPI-C6)-lift-off process. Five nm titanium (Ti, 99.999%) and 50 nm gold (Au, 99.999%) were selected as electrode metals to be deposited on the sample surface by the thermal evaporation method, where the role of Ti is to increase the electrode adhesion on MoS₂.

B. Characterization and Measurement

Room-temperature Raman spectroscopy measurements were carried out in a confocal microscopy setup with a 514 nm solid-state green laser for excitation with the power maintained below 0.25 mW. Temperature-dependent measurements ranging from 300 to 500 K were carried out using a hot plate with adjustable temperature, and samples were allowed for thermal stabilization of 5 min. The XPS was carried out using a VG ESCALAB 220i-XL system with a constant pass energy of 20 eV and a monochromatic Al K_α (1486.6 eV) X-ray source. The core-level binding energy was corrected using C 1s peak at 284.8 eV in order to exclude the sample surface differential charging effect. The lithography process was carried out using a UV contact exposure mask aligner (Munich, MA6) with a power of 365 W. TEM was carried out using an America FEI-Titan Cubed Themis G2 300 with TEM information resolution (nonlinear) of 0.06 nm. The electrical performance characteristics of the related photodetectors were investigated by a Keithley 4200-SCS semiconductor analyzer.

C. Theoretical Simulation

The first-principles calculations involved in this work were performed using the Cambridge Sequential Total Energy Package (CASTEP) based on DFT [33]. Various parameters were set as follows. The maximum Hellmann–Feynman forces were 0.05 eV/Å, the electronic wave functions were expanded in a plane-wave basis set with energy cut-off of 650 eV to ensure convergence, and a $5 \times 5 \times 1$ Monkhorste-Pack mesh was used in the Brillouin-zone sampling. The total energy changes during the optimization finally converged to less than 10^{-6} eV/atom, the maximum force each atom in the crystal was less than 0.03 eV/nm, the maximum stress in the crystal

was less than 0.05 GPa, and the maximum displacement of the atom was less than 0.0001 nm.

3. RESULTS AND DISCUSSION

In order to achieve a high-quality, uniform, and continuous multilayer MoS₂ film, a transparent 1 cm × 1 cm FS GaN with nearly perfect lattice matching was selected as the deposited substrate in this work. The Raman spectrum at room temperature shown in Fig. 1(a) detected two Raman peaks at 384.04 cm⁻¹ and 405.37 cm⁻¹, which are, namely, E_{2g}¹ mode-related to in-plane atom vibration and A_{1g} mode-related to out-of-plane vibration, respectively. The distance between the two peaks was 21.33 cm⁻¹, which indicates that the number of layers of MoS₂ is about five to six layers. Mo 3d_{3/2} (233.44 eV), Mo 3d_{5/2} (230.03 eV), and S 2s (227.57 eV) peaks were exhibited in the XPS spectrum shown in Fig. 1(b), which is consistent with the reported values [34]. In addition, the peak related to Mo–O bonding was not found near 235.7 eV, implying that no byproduct MoO_x was produced during the growth of MoS₂. The atomic ratio of S and Mo is about 1.97, which is close to stoichiometric MoS₂ [35,36]. Subsequently, Al₂O₃ stress liner with 3 nm thickness was deposited on the MoS₂/GaN sample using ALD. Cross-section TEM was carried out on the Al₂O₃/MoS₂/GaN sample, as shown in Fig. 1(c); the TEM image can be divided into three parts: the thickness of the uppermost part is about 3 nm, the middle part shows a clear layered structure with about 4 nm thickness (corresponding to six layers), and the bottom part has a crystal structure. Combining the distribution curve of

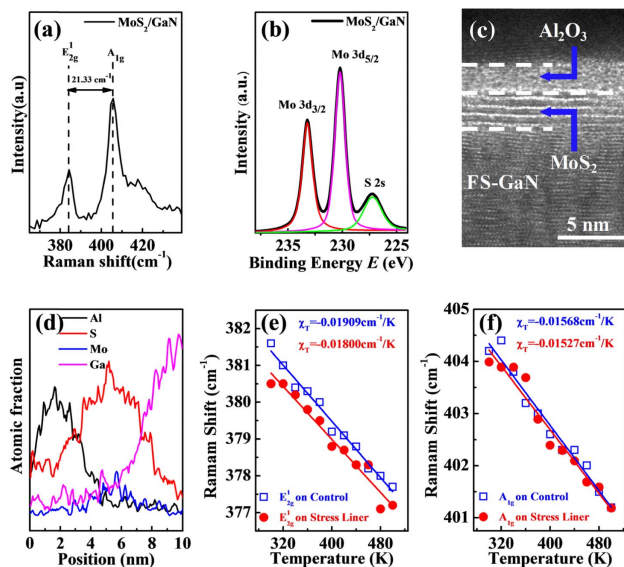


Fig. 1. Material characterization of multilayer MoS₂ with and without Al₂O₃ stress liner. (a) Raman spectra of multilayer MoS₂ sample grown on FS GaN substrate; the distance between E_{2g}¹ and A_{1g} is 21.33 cm⁻¹; (b) core level XPS spectrum of Mo 3d and S 2s of the control multilayer MoS₂/GaN sample; (c) cross-sectional TEM image of the multilayer MoS₂/GaN with 3 nm Al₂O₃; (d) Al, S, Mo, and Ga element fraction as a function of depth position. The position of Raman mode peaks for (e) E_{2g}¹ and (f) A_{1g} of control and stress liner samples as a function of temperature including a linear fit.

atomic fraction with the position shown in Fig. 1(d) by starting straight down along the surface of Al₂O₃, these three parts are Al₂O₃, MoS₂, and GaN.

The investigation of temperature-dependent vibrational properties is important for further understanding the electron–phonon interaction, transport properties, and crystal structure of materials, which may largely impact the performance of photoelectronic devices. In this work, temperature-dependent Raman spectra also were determined on the MoS₂/GaN sample (control) and Al₂O₃/MoS₂/GaN sample (stress liner) to investigate the lattice vibration properties. The Raman spectral curves of control and stress liner samples as a function of temperature variation from 300 to 500 K with a step of 20 K are shown in Figs. S1(a) and S1(b), respectively (see Dataset 1, Ref. [37]). Obvious redshifts of the two peaks in both samples can be observed with the temperature rising, similar to those of the other 2D materials [38–41]. Extracted peak positions of E_{2g}¹ and A_{1g} Raman modes for both samples are shown in Figs. 1(e) and 1(f), respectively. These points can be fitted using this formula [42]: $\omega = \omega_0 + \chi_T \Delta T$, where ω_0 is the mode frequency measured at 300 K, χ_T is the first-order temperature coefficient, and ΔT is the temperature difference relative to 300 K. For the stress liner sample, fitted χ_T values of E_{2g}¹ and A_{1g} were about 0.01800 and -0.01527 cm⁻¹/K, respectively, the absolute values of which were smaller than the corresponding values (-0.01909 and -0.01568 cm⁻¹/K) of the control sample. Smaller χ_T in the former demonstrated a better thermal stability, and these results were consistent with previous reports that an Al₂O₃ capping layer significantly improves the thermal stability of black phosphorus [43,44]. A possible reason for the improvement of thermal stability is the tensile strain on MoS₂ introduced by Al₂O₃, which can soften the phonon vibrations and reduce thermal conductivity of MoS₂ [45].

In order to explore the distribution of the stress after covering 3 nm Al₂O₃, the variation of stress on MoS₂ with position was simulated and is shown in the cross-sectional view of Fig. 2(a), which is in the photodetector of the same proportion. The strain ϵ in major MoS₂ was calculated to be about 0.58% with a stress σ of 1.35 GPa using the formula: $E_{\text{Young}} = \sigma/\epsilon$, where E_{Young} is Young's modulus taking $E_{\text{Young}} = 238$ GPa [46]. MoS₂ under Ti/Au is in a compressed state, and MoS₂ under Al₂O₃ is in a stretched state. Along the horizontal direction of MoS₂, the stress as a function of position is shown in Fig. 2(b). There was a maximum of tensile stress near the intersection of the MoS₂, Al₂O₃, and Ti/Au (location = 0.495 μm). The conduction and valence bands of MoS₂ changed due to the introduction of this tensile strain. First-principle calculations based on DFT were used to simulate the band structure of six-layer MoS₂ with and without tensile strain. Figure 2(c) shows the changes at the bottom of the conduction band and the top of valence band with 0%–2% biaxial tensile strain. Unstrained multilayer MoS₂ exhibits an indirect bandgap, and as the strain increases, the conduction band moves downward, the K point of the valence band moves downward, and the bandgap decreases linearly from 1.65 eV without strain to 1.20 eV at 2% biaxial tensile strain, shown in Fig. 2(d), which is similar to the case of a monolayer MoS₂

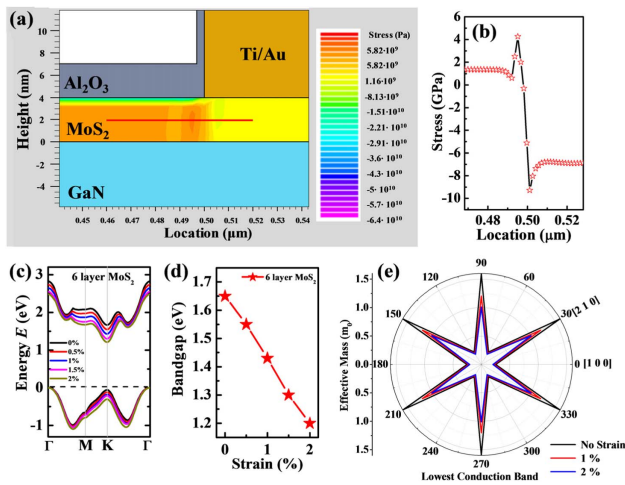


Fig. 2. Simulation of multilayer MoS₂ with tensile strain. (a) 2D stress mapping within the multilayer MoS₂ (4 nm) photodetector with Al₂O₃ stress liner; (b) horizontal stress distribution within the multilayer MoS₂ layer. Results of first-principles calculations: the variation of (c) the bottom of the conduction band and the top of the valence band, (d) bandgap, and (e) electron effective mass under different tensile strain on six-layer MoS₂.

[24]. Furthermore, the electron effective mass of the lowest conduction band can be estimated by the formula: $m^* = \hbar^2 / (\partial^2 E / \partial^2 k)$, where \hbar is the reduced Planck constant. As shown in Fig. 2(e), the electron effective mass of six-layer MoS₂ decreases with increasing biaxial tensile strain, which is related to the enlargement in the degree of bending at the bottom of the conduction band and beneficial in enhancing the electron mobility of MoS₂.

A transparent photodetector array with two identical (5 nm) Ti/(50 nm) Au electrodes was fabricated on a MoS₂/GaN sample with a size of 1 cm by 1 cm using a semiconductor processing technology (control photodetector). Figure 3(a) shows a 3D schematic view of the MoS₂ photodetector; about 3 nm Al₂O₃ was deposited via ALD at the surface of the detector (stress liner photodetector). The photoelectric performance of both photodetectors was fully characterized, and the current (absolute value) curves as a function of voltage V (from -20 to 20 V) under dark and 365 nm light with different powers are exhibited in Fig. 3(b). For the control device, the dark current was about 94.6 nA at 20 V, indicating the multilayer MoS₂ grown on GaN was undoped, and the Fermi level resided in the bandgap [47]. At the same voltage, the 365 nm laser irradiation with 5.647 μ W power made the current increase by 3 orders of magnitude due to the generation of photocarriers in the material, which is considered as optical doping [48]. For the stress liner photodetector, a significant increase in dark current can be observed after Al₂O₃ stress liner, which is due to reduced bandgap under tensile strain.

Similarly, the current was also greatly increased by the generation of photocarriers under different powers of illumination for the stress liner photodetector. Photocurrent I_{ph} can be extracted by the equation: $I_{ph} = |I_{light}| - |I_{dark}|$, where I_{dark} and I_{light} are the current in dark condition and under illumination, respectively. Figure 3(c) shows the scattered point distribution

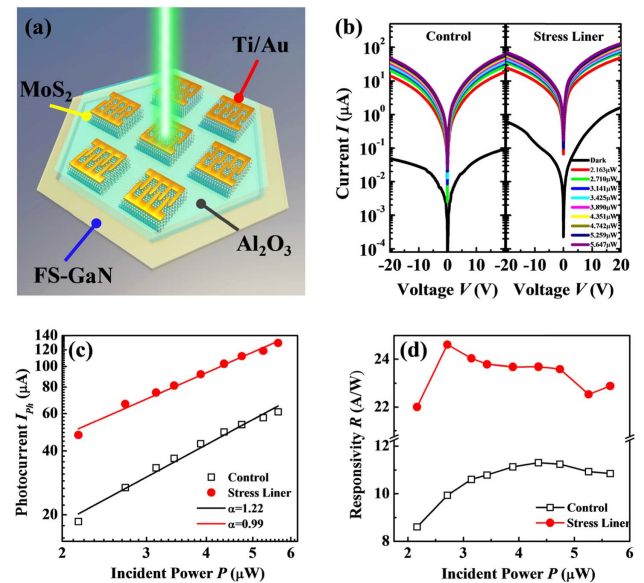


Fig. 3. Schematic and measurement of MoS₂ photodetector with and without Al₂O₃ stress liner. (a) 3D schematic structure view of multilayer MoS₂ photodetectors with the Al₂O₃ stress liner; (b) dark current and light current as a function of voltage under different power of the 365 nm incident light for control and stress liner photodetector; (c) extracted photocurrent of two photodetectors at 20 V with varying incident power. The straight lines were fitted by the power law ($I_{ph} \propto P^\alpha$). (d) Calculated responsivity of two photodetectors as a function of incident power.

of the photocurrent under different incident powers with 365 nm wavelength at 20 V voltage, and more than twice the increase of the photocurrent could be observed in the stress liner photodetector due to tensile strain in comparison with the control photodetector. For both photodetectors, linear increases of photocurrent with incident power could be fitted using the power law $I_{ph} \propto P^\alpha$. The values of α decreased from 1.22 of control to 0.99 of the stress liner photodetector, implying routes of the loss of the photoexcited carrier by a recombination existed [49,50], and both the defects of the MoS₂ and the charge impurities around the MoS₂ could be recombination centers. Similar behavior exists in other nanomaterials reported, such as monolayer MoS₂ [51,52], Si [53], ZnO [49], and GaN nanowires [50]. Responsivity is a measure of the photoelectric conversion characteristics of a photodetector and the spectral and frequency characteristics of the photoelectric conversion, which was calculated by using the equation: $R = I_{ph} / P_{in}$, where P_{in} is the power of the incident light irradiated to the active part of the photodetector, which is normalized by the equation: $P_{in} = P_0 / (\text{power density} \times \text{active area})$, where P_0 is the output power of the laser source. The calculated R values of control and stress liner photodetectors are plotted as a function of laser incident power under a bias voltage of 20 V in Fig. 3(d). The responsivity R values of the control photodetector showed a trend of rising as the irradiation power increased and then decreased, and the achieved maximum R was about 11.30 A/W at $P = 4.351 \mu$ W, which is because carrier lifetime increases resulting in the carrier recombination became less frequent at low excitation power [54], which is ascribed to the

reduced carrier recombination rate. Due to tensile strain effect, the extracted highest achievable responsivity value in stress liner photodetector was 24.62 A/W at $P = 3.141 \mu\text{W}$, which is more than twice the corresponding value of the control photodetector. Due to the high quality of the multilayer MoS₂ grown in this work, the photocurrent and responsivity are higher than that of the previously reported monolayer MoS₂ photodetectors [5,7,8]. The enhancement in photocurrent and in responsivity indicates that tensile strain effectively improves the performances of the MoS₂ photodetector, which is consistent with the results reported by Kuo *et al.* [29].

To further evaluate the performance of both photodetectors, photoconductive gain G and external quantum efficiency (EQE) were also estimated and are shown in Fig. 4(a). Photoconductive gain G , representing the number of carriers in the photocurrent, can be generated by one absorbed photon, and is estimated by the equation: $G = (I_{\text{ph}}/P_{\text{abs}})(h\nu/q)$, where P_{in} is incident power, ν is the frequency of the incident laser, h is the Planck constant, q is the elementary charge, and P_{abs} is the absorbed power defined as $P_{\text{abs}} = \mu P_{\text{in}}$. In order to acquire the absorption percentage μ , the absorbance curves of the MoS₂/GaN sample were also measured in this work, which were obtained by subtracting the absorbance of the blank GaN substrate and plotting it as a function of the incident wavelength shown in Fig. S2 (see Dataset 1, Ref. [37]). Due to the “absorbance A ,” which is defined as $A = \log_{10}(I_0/I_t)$, where I_0 and I_t are the intensity of incident light and transmitted light, respectively, the absorption percentage μ can be obtained by $\mu = 1 - 1/10^A$. When the wavelength is 365 nm, μ is about 16.13% using $A = 0.0764$. The maximum value of photoconductive gain G in the stress liner photodetector is 520, which is much bigger than the corresponding maximum value 239 of the control photodetector, demonstrating that MoS₂ with an Al₂O₃ stress liner can generate more carriers contributing to the photocurrent due to tensile strain effect. EQE refers to the average number of electrons released in the photodetector resulting from each incident photon. It is related to the energy of the incident laser, and expressed by $\text{EQE} = R(h\nu/q)$. Similarly, the highest values of the extracted EQE are 3848% for the control photodetector and 8381% for the stress liner photodetector. Such a significant increase in EQE illustrates that tensile strain can increase the number of electrons generated per incident photon per unit time.

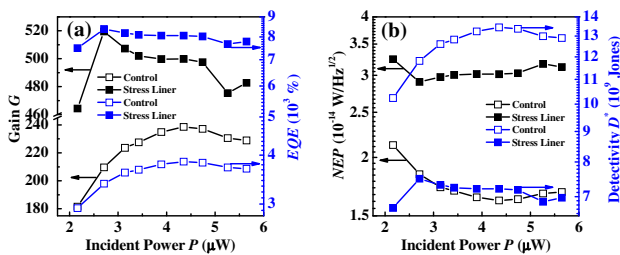


Fig. 4. Performance of control and stress liner photodetectors. (a) Gain and EQE as a function of incident power; significant increases in both values for stress liner photodetector; (b) NEP and detectivity as a function of incident power; reduced performance of both for stress liner photodetector due to the increase in dark current.

Noise equivalent power (NEP) and normalized detectivity (D^*) are parameters that describe the detection capability of a photodetector. Lower NEP and higher D^* indicate a better detection capability of photodetectors. NEP and D^* are estimated by the equations: $\text{NEP} = \sqrt{2qI_{\text{dark}}\Delta f}/R$ and $D^* = \sqrt{A}/\text{NEP}$, respectively, where I_{dark} is the current in the dark state and Δf is the bandwidth. Herein, we use $\Delta f = 1$, and the active area A of the device refers to the part where the two electrodes face each other and is calculated as $47,000 \mu\text{m}^2$. As the Fig. 4(b) shows, NEP increases and D^* decreases can be observed in the MoS₂ photodetector with the Al₂O₃ stress liner. Compared to the multilayer MoS₂ photodetector grown on sapphire, the MoS₂/GaN photodetector has better detection capabilities due to the near-perfect lattice matching [6]. The reduction of the detection capability can mainly be attributed to the enlargement of the bandgap of MoS₂, the increase of the carrier concentration, and the dark current of the photodetector under the effect of tensile strain.

Finally, the time-response behavior for both photodetectors was measured using a 365 nm light at a power of $5.642 \mu\text{W}$, alternately switched on/off every 10 s. The photocurrent for two photodetectors as a function of time under a fixed voltage 20 V is shown in Fig. 5(a). A repeatable and stable photo-switching behavior is observed. In addition, the corresponding rise time, taken from 10% to 90% of maximum photocurrent, and the fall time, taken from 90% to 10% of maximum photocurrent, are shown in Figs. 5(b) and 5(c), respectively, which were obtained by selecting and zooming in on one of the cycles in the curves. In comparison, the rise time was reduced from

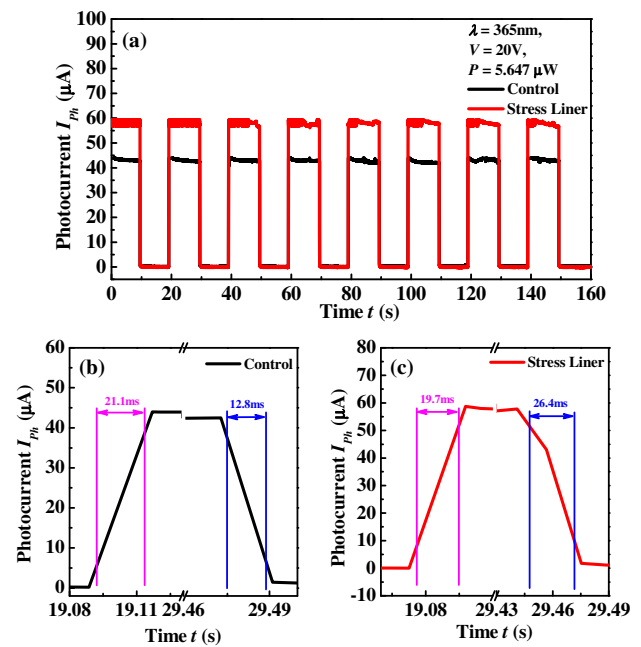


Fig. 5. Time curve of photocurrent with a switch on/off light. (a) Photocurrent-time curve of control and stress liner photodetectors illuminated by 365 nm light source with the incident power of $5.647 \mu\text{W}$ at 20 V, respectively. The corresponding rise time (from 10% to 90% of maximum photocurrent) and the fall time (from 90% to 10% of maximum photocurrent) of (b) control and (c) stress liner photodetector, respectively.

21.1 s of the control photodetector to 12.8 s of the stress liner photodetector, and the corresponding fall time was increased from 19.7 to 26.4 s. The shortening current rise time is mainly due to the increased electron mobility induced by decreased electron effective mass of MoS₂ under tensile strain effect, and the extended current fall time is mainly owing to the carriers being captured by the defects existing in Al₂O₃.

4. CONCLUSION

High-quality continuous multilayer MoS₂ was prepared on an FS GaN substrate using CVD and characterized by Raman spectroscopy and XPS. ALD was used to deposit 3 nm Al₂O₃ on a MoS₂/GaN sample. Temperature-dependent Raman spectroscopy was carried out to demonstrate that the thermal stability of MoS₂ was improved due to the tensile strain effect induced by Al₂O₃. The theoretical simulation shows that the multilayer MoS₂/GaN with 3 nm Al₂O₃ stress liner is stretched, which results in reduction of the bandgap and electron effective mass. Under illumination of 365 nm, a state-of-the-art performance was demonstrated in the stress liner photodetector, leading to a responsivity of 24.6 A/W, a gain of 520, and an EQE of 8381%. These are more than twice the corresponding values of the control photodetector. The shortened current rise time under illumination is due to improved electron mobility by introducing tensile strain. This work demonstrates an effective method to improve the performance of 2D material photodetectors and may guide the development of next-generation imaging systems.

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